



MCh Data Management

Issue 0 – 28.05.2025

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Discussion Format

- Possible formats:
 - discussions (steps 1 & 2)
 - discussion + email / wiki (step 1 + step 4 / 6)
 - emails (steps 3 & 4)
 - wiki (steps 5 & 6)
 - wiki + email (step 5 + step 4)
- Discussions:
 - introduction of topics to think about or discuss (step 1)
 - discussion about the topics during the following Wednesday meeting (step 2)
- Emails:
 - writing a list of topics to think about or discuss and sending it through an email (step 3)
 - collecting replies from MCh researchers (step 4)
- Wiki:
 - writing a list of topics to think about or discuss on a dedicated mch-wiki page (step 5)
 - gathering replies via polls or discussion over the mch-wiki (step 6)

General Information

- MCh RDM templates:
 - accessible to every MCh employee
 - the up-to-date templates located on my “Exchange” disk:

J:\Fecik,Michal\rdm_templates

- please, get familiar with the templates you will most likely use in future
- once finished, the templates are going to be also uploaded to mch-wiki

All newly accepted changes will be mirrored in the templates and will be communicated via a selected channel (see below).

- How to be informed about changes:
 - short summary during Wednesday meetings
 - summary sent by email
 - summary provided on a dedicated mch-wiki page

Deposition Template(s)

- Units:
 - prefill (but allow editing) vs. offer prefilled selection to choose from (drop-down menu)?
- Gas Supply:
 - store gas flow (allow both % and SCCM) instead of just a partial pressure?
 - store also information about used mass flow controller (MFC)
 - allow keeping also the partial pressure?
- Magnetrons:
 - in what manner to store magnetron material & its composition
 - *example: “material system”: “Cr-Al-B”; “composition”: “0.78-0.22-2”*
 - store orientation of magnetrons
 - preferentially as a pictogram in a particular sheet of the template (other options?)
 - store information about pre-sputtering for each single magnetron, or just the chamber as a whole?
 - if pre-sputtering done
 - with what shutter
 - for how long
 - how to store sputter-cleaning information?
 - create a particular metadatum, or in comments?

Deposition Template(s)

- Substrate:
 - store origin of substrates?
 - how to store “no intended heating”? (add to description/comments, create specific metadata structure)
 - *example: “heating”: “yes”; “heater temperature”: “xyz” OR “heating”: “no”; “heater temp.”: --empty—*
 - substrate temperature related information:
 - add power of heating spiral(s) (case of CemeCon)
 - allow storing % of power for heating (case of Kybele)
 - store voltage & current on heating units (case of Jarvis or Garfield)
- Generators:
 - store maximal as well as current value of a fixed parameter (HPPMS mode)
 - two voltage or power channels for RF mode? (forward & reflected)
- General:
 - add comment metadata to store generic information? (formatting limitations, visually less distinct)
 - in what form store deposition material system?
 - *example: “material system”: “Cr-Al-B”*
 - store also expected or wanted composition?